

3. (Original) An evaluation method for polycrystalline silicon as set forth in claim 1, wherein the polycrystalline silicon immersed in the agent is aggregated or in pellet shape.

4. (Original) An evaluation method for polycrystalline silicon as set forth in claim 2, wherein the polycrystalline silicon immersed in the agent is aggregated or in pellet shape.

5. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 1, further comprising the step of:

analyzing the composition of the foreign particles.

6. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 2, further comprising the step of:

analyzing the composition of the foreign particles.

7. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 1,

wherein said foreign particles cause crystal defects.

8. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 5, wherein the analysis is carried out using scanning electron microscopy ~~of~~ or energy dispersive X-ray spectroscopy.

9. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 1, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

10. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 2, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

11. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 3, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

12. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 4, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

13. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 5, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

14. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 6, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

15. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 7, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

16. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 8, further comprising the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

17. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 1, wherein counting the number of foreign particles includes using a measuring device.

18. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 17, wherein the measuring device is a particle counter.

19. (Previously presented) An evaluation method for polycrystalline silicon as set forth in claim 1, wherein the agent is hydrofluoric acid and nitric acid.

20. (New) An evaluation method according to claim 1, wherein said agent is an etchant.